Amendments to the Specification:

Page 8, amend the paragraph beginning on line 16 to read as follows:

~~FIG. 1 is a~~ FIGs. 1(a) and 1(b) are perspective ~~view~~ views showing the overall structure of a vacuum processing apparatus according to the preferred embodiment of the present invention;

Page 8, amend the paragraph beginning on line 19 to read as follows:

FIG. ~~2~~ 2(a) is a plan view and FIG. 2(b) is a side view showing the outline structure of the vacuum processing apparatus according to the embodiment of the present invention;

Page 8, amend the paragraph beginning on line 22 to read as follows:

~~FIG. 3 is a~~ FIGs. 3(a) - 3(d) are perspective ~~view~~ views showing the outline structure of each unit of the vacuum processing apparatus according to the embodiment of the present invention;

Page 17, amend the paragraph beginning on line 7 to read as follows:

A gap is formed between the rear surface of the box 108 and the ~~fame~~ frame 106 of the processing block 102, this gap providing a space in which a user can enter and work on the processing units 104, the transfer chamber 112 and the lock chamber 113, and also providing a space in which the user can confirm the display 202 on the rear of the box 108 and the connection interface unit 201 or enter orders via the control means etc. Further, means for controlling and displaying information on the operation of apparatuses related to the supply lines are collectively disposed

in this space. Thus, the work related to operating the apparatus is facilitated, and the operation efficiency of the apparatus is improved.

Page 25, amend the paragraph beginning on line 15 to read as follows:

Furthermore, a process gate valve 513 for opening and closing the process gate is located in a space interposed between the outer chamber 511 and the inner chamber 509, the process gate valve ~~514~~ 513 capable of being moved both in vertical and horizontal directions via a driving means 521 disposed below the valve ~~514~~ 513. In order to shut the gate, the valve 513 is disposed on the side wall of the inner chamber 509 sealing the gate at the ~~inner~~ outer side of the side wall, and in order to open the gate, the valve 513 is removed therefrom. The location and shape of the process gate is determined so as not to interfere with the wafer and the robot arm when the wafer is being transferred by the robot arm disposed within the transfer chamber. Further, the shape of the process gate is designed so that when the gate is closed by the process gate valve 513, the inner walls of inner chambers 509 and 510 do not become uneven.